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January 31, 2006 amendment Serial No.08/544,212

Amendments to the claims:

This listing of claims will replace all prior versions and listings of claims in the application:

Listing of Claims:

The listing of claims starts on the following page.

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- 1. A gaseous composition at a temperature below about 100° C, at atmospheric pressure, adapted to deposit at least a first layer of tin oxide and silicon oxide onto glass at a rate of deposition greater than about 350 Å/sec, wherein the composition comprises a precursor of tin oxide, a precursor of silicon oxide of formula R.mO.,Sip. where m is from 3 to 8, n is from 1 to 4, and R is independently chosen from hydrogen and acyi, itraight, cyclic, or branched-chain alkyl and substituted alkyl or sikenyl of from one to about mx carbons, and phenyl or substituted phenyl, an accelerant selected from the group consisting of organic phosphites, organic borates and water, and mixtures thereof, and a source of oxygen.
- The gaseous composition of claim 1, adapted to deposit at least a first layer comprising tin oxide and silicon oxide onto transparent flat glass at a temperature of from 450° to about 650° C.
- 3. The gaseous composition of claim 1, adapted to deposit at least a first layer comprising tin oxide and silicon oxide onto transparent flat glass to produce a glass article having essentially so reflected color in daylight.
- 4. The gaseous composition of claim t adapted to continuously deposit at least a first layer of tin oxide and silicon oxide onto a continuously moving transparent flat glass substrate.
- 5. The composition of claim 1 at a temperature below about 175° C.
- 6. The composition of claim 1 wherein the organic phosphite and organic borate accelerants have the formula (R"O)₃P and (R"O)₃B where R" is independently chosen from straight, cyclic or branched-chain alkyl or alkenyl of from one to about six carbons; phenyl, substituted phenyl, or R" CH₂CH₂—, where R" is MeO₂C—, EtO₂C—, CH₃CO—, or HOOC—.
- 7. The composition of claim 1 wherein the precursor of the tin oxide is R₀SaX₄₋₈, where R is a straight, cyclic, or branched-chain alkyl, or alkenyl of from one to about six carbons; phenyl, substituted phenyl, or R'CH₂CH₂₋, where R' is MeO₂C₋, EtO₂C₋, CH₃CO₋, or HO₂C₋; X is selected from the group consisting of halogen, acetate, perfluoroscetate, and their mixtures; and where a is 0, 1, or 2.
- The composition of claim 1 wherein the precursor of the tin oxide is an alkyltin halide.
- The composition of claim 1 wherein the precursor of the tin oxide is an alkyltin chloride.
- 10. The composition of claim I wherein the precursor of the tin oxide is chosen from the group consisting of monoburylytin trichloride, diburylytin dichloride, triburylytin chloride, and tin tetrachloride.
- 11. The composition of claim 1 wherein the precursor of silicon oxide is selected from the group consisting of tetraethylorthosilicate, discetoxydi-t-butoxysilane, ethyltriacetoxysilane, methyltriacetoxysilane, methyltriacetoxysilane, methyldisiloxane, tetraramethyldiscotoxysilane, dipinacoloxysilane, 1,1-dimethylsila-2-oxacyclohexane, tetrakis (1-methoxy-2-propoxy) silane, and triethoxysilane.

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- 12. The composition of claim i wherein the precursor of silicon oxide is tetraethylorthosilicate.
- The composition of claim I wherein the accelerant comprises triethyl phosphite.
- 14. The composition of claim 1 wherein the accelerant comprises triethyl phosphite and triethyl borate.
- 15. The gaseous composition of claim 1 adapted to deposit at least a first layer of the oxide and silicon oxide outo glass at a rate of deposition greater than about 400 A/sec.
- 16. The gaseous composition of claim 1 adapted to deposit at least a first amorphous layer of tin oxide and silicon oxide onto glass.
- 17. The gaseous composition of claim 1 adapted to deposit a plurality of layers comprising tin oxide and silicon oxide onto glass, the outermost layer of which is further adapted for deposit of at least a second layer.
- The composition of claim 17 adapted to deposit a plurality of layers comprising tin oxide and silicon oxide

onto glass, the outermost layer of which is further adapted for deposit of a layer comprising tin oxide.

- 19. The composition of claim 17 adapted to deposit a plurality of layers comprising tin oxide and silicin exide onto glass the outermost layer of which is further adapted for deposit of a layer comprising tin oxide and fluorine.
- 20. The composition of claim 17 wherein the second layer comprises a doped tin oxide.
- 21. The composition of claim 17 wherein said pluratity of layers are deposited from a precursor mixture comprising monobutyltin trichloride, tetraethyl orthosilicate and triethyl phosphite.
- 22. The composition of claim 1 adapted to deposit at least a first layer comprising in oxide and silicon oxide onto glass, said first layer having a refractive index which changes continuously between the glass substrate and the top of the layer.
- 23. A gaseous composition at a temperature below about 200° C. at atmospheric pressure, adapted to deposit at least a first amphorous layer comprising tin oxide and silicon oxide onto glass at a rate of deposition greater than about 400 Å/sec., the layer having a controlled index of refraction, wherein the composition comprises a tin oxide precursor, a silicon oxide precursor of formula R_mO₀Si_p, where m is from 3 to 8, n is from 1 to 4, p is from 1 to 4, and R is independently chosen from hydrogen and acyl, straight, cyclic, or branched-chain alkyl and substituted alkyl or alkenyl of from one to about six carbons, and phenyl or substituted phenyl, and at least one accelerant chosen from the group consisting of boron and phosphorous esters and water.
- 24. The gasous composition of claim 23 adapted to continuously deposit at least a first layer comprising no oxide and silicon oxide onto a continuously moving flat glass substrate at a temperature of from about 450° to about 650° C., and comprising monobutyltin trichloride, tetraethyl orthosilicate and an accelerant.
- 25. A gaseous composition at a temperature below about 200° C, and at atmospheric pressure, adapted to deposit at least a first tayer comprising amorphous in

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oxide and silicon oxide onto glass at a temperature of front about 450° to 650° C, at a rate of deposition greater than about 350 Å/sec., wherein the composition comprises:

a tin oxide precursor of formula R.SnX4..., where R is a straight, cyclic, or branched-chain alkyl, or alkenyl of from one to about six carbons: phenyl, substituted phenyl, or R'CH3CH1..., where R' is MeO1C... EtO2C... CH3CO... or HO2C... X is selected from the group consisting of halogen, acetate:, perfluoroacetate, and their mixtures; and where n is 0, 1, or2;

a silicon oxide precursor of formula R_mO_nSi_p, where m is from 3 to 8, n is from 1 to 4, p is from 1 to 4, and R is independently chosen from hydrogen and acyl, straight, cyclic, or branched-chain alkyl and substituted alkyl or alkenyl of from one to about six carbons, and phenyl or substituted phenyl;

one or more accelerants selected from the group consisting of water and organic phosphites and organic borates of formula (R"O)₃P and (R"O)₃B where R" is independently chosen from straight, cyclic or branched-chain alkyl or alkenyl of from one to about six carbons: phenyl, substituted pheny, or R" CH₂CH₂—, where R" is MeO₂C—, EtO₂C—, CH₃CO—, or HOOC—; and

a source of oxygen.

26. A composition according to claim 25 in which the precursor of the tin oxide is an alkylin halide, the precursor of the silicon oxide is tetraethylorthosilicate, discetoxydi-t-butoxysilane, ethyltriscetoxysilane, methyltriscetoxysilane, methyldiscetoxysilane, tetramethyldisiloxane, tetramethylcyclotetrasiloxane, dipinacoloxysilane, 1.1-dimethylsila-2-oxacyclohexane, tetrakis (1-methoxy-2-propoxy) silane, or triethoxysilane, and the accelerant comprises one or both of triethyl phosphite and triethyl borate.

27. A composition according to claim 26 in which the tin oxide precursor comprises monobutyltin trichloride, the silicon oxide precursor comprises tetraethyl orthosilicate and the accelerant comprises triethyl phosphite.

Claims 28, 29, 31-60, 65 and 66; (canceled without prejudice or disclaimer).